

Changes in Aspect Ratio and Geometric Axis Orientation of Crystalline Grains of $\text{Ni}_{80}\text{Fe}_{20}$ Electrodeposited on Nanostructured Copper Cathodes

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Abstract.

$\text{Ni}_{80}\text{Fe}_{20}$ films ($t=15\text{nm}$) were electrodeposited on a nanostructured copper sheet [Ref.1]. Multistep electropolishing of the sheet ensured rms roughness $\sim 7\text{nm}$ over $50 \times 50 \mu\text{m}^2$ areas [Ref.2]. Parallel scratches arise (Fig.1) mechanically polishing copper unidirectionally ($\#9\mu\text{m}$ diamond paste). Fig.2. shows a typical cross section. Scratches of interest are approximately dihedral with medium deepness $\sim 100\text{nm}$ and medium top width $\sim 1000\text{nm}$ ($\beta \sim 2\arctan(5)$) [Ref.3]. Electrodeposition on resulting spatial charge distribution implied on elongation of grains and orientation of its main axis parallel to scratching direction (Fig.4). Fig.3. shows the isotropic aspect ratios and orientation of an equivalent film, deposited on a non-structured copper evaporated film.

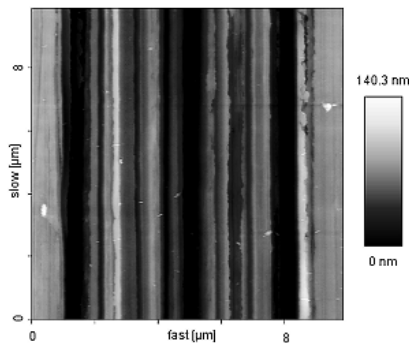


Figure 1: AFM image of a nanostructured copper sheet with parallel scratches.

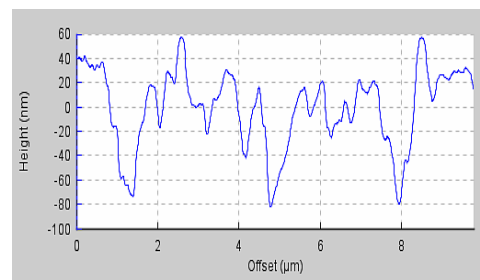


Figure 2: Typical cross section of the parallel nanoscratches on copper.

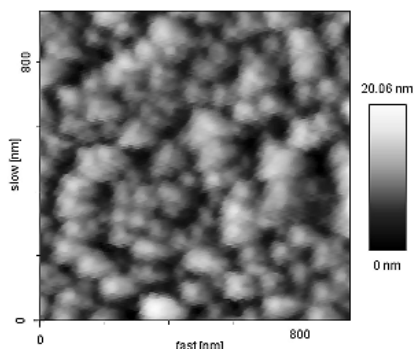


Figure 3: AFM image of a typical isotropic grain morphology of a 15 nm $\text{Ni}_{80}\text{Fe}_{20}$ film electrodeposited on a flat Cu evaporated film.

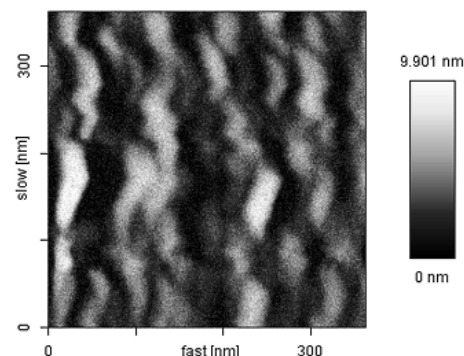


Figure 4: AFM image of the anomalous morphology of a 15 nm $\text{Ni}_{80}\text{Fe}_{20}$ film electrodeposited on a nanostructured Cu substrate, showing one of the internal faces of a dihedral, with elongated grains aligned parallel to scratches.

References

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- [3] Jackson, J.D, "Classical Electrodynamics", John Wiley & Sons, 2nd Ed., p. 75, 1975.